

<b>Notice of References Cited</b>	Application/Control No. 09/917,095	Applicant(s)/Patent Under Reexamination YAMAZAKI ET AL.	
	Examiner Evan T. Pert	Art Unit 2829	Page 1 of 1

**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-			
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**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Z. Jian-ming, "Optimization of Glow Discharge Deposition of Amorphous Silicon Films", 1988, 20 <sup>th</sup> IEEE Photovoltaic Specialists Conference, vol. 1, pages 296-300.
	V	
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\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
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